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 UNITED NATIONS EDUCATIONAL, SCIENTIFIC AND CULTURAL ORGANIZATION
INTERNATIONAL CENTRE FOR THEORETICAL PHYSICS
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UNITED NATIONS INDUSTRIAL DEVELOPMENT ORGANIZATION



INTERNATIONAL CENTRE FOR SCIENCE AND HIGH TECHNOLOGY

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SMR/542 - 7

ICTP-INFN
SECOND COURSE ON BASIC VLSI DESIGN TECHNIQUES
 18 February - 15 March 1991

*Analogue Integrated Circuits Technology
 and Design Techniques
 - Introduction -*

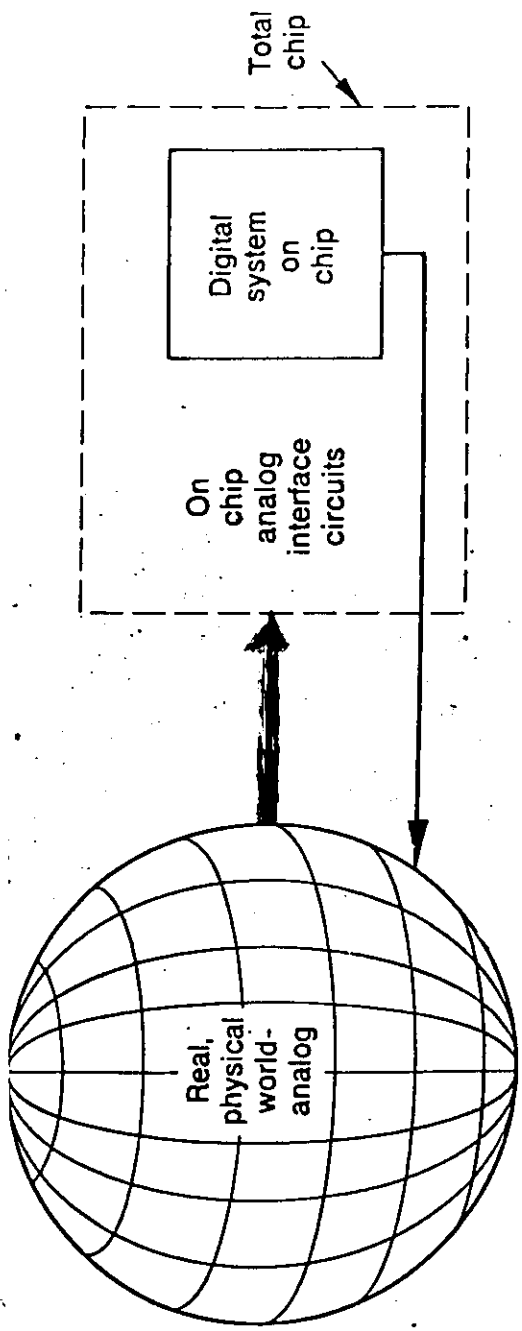
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Analogue Integrated Circuits Technology & Design Techniques for Large Scale Integration

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VLSI Design Centre (Dept. of Elec. Govt. of India)
 Centre for Development of Advanced Computing
 Pune - 411007 INDIA

These are preliminary lecture notes, intended only for distribution to participants.



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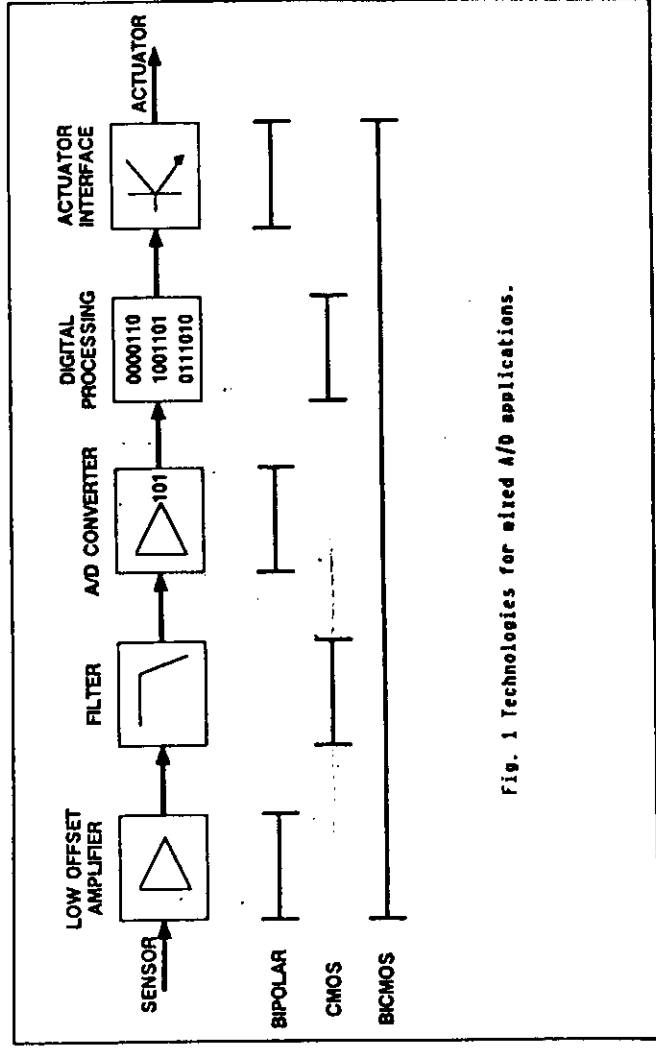
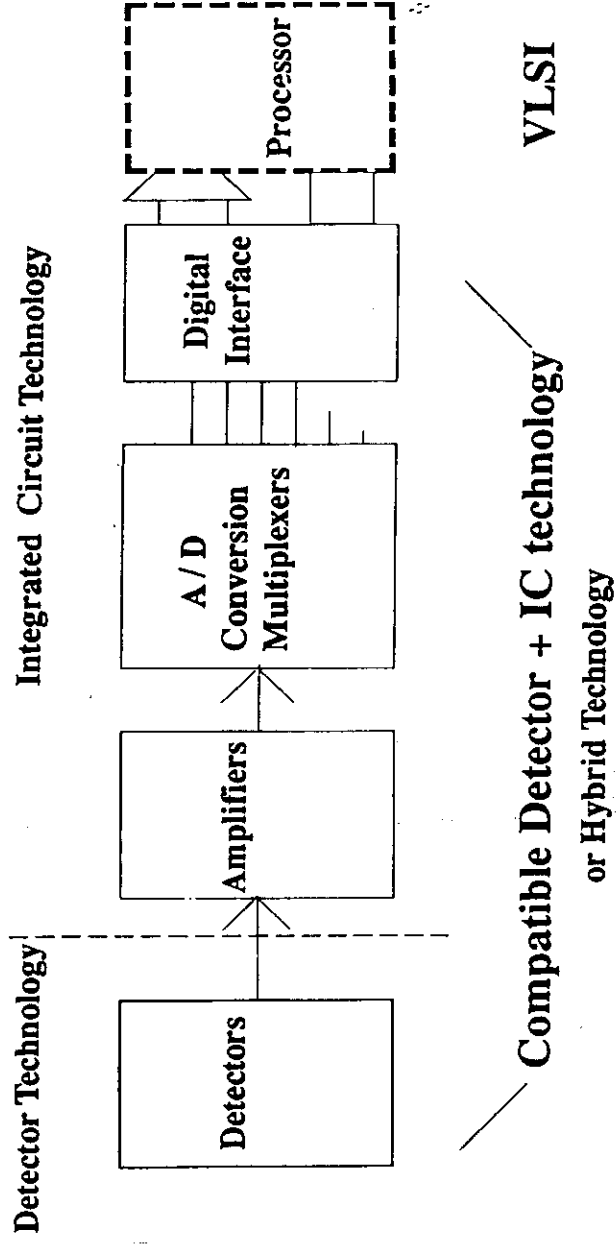


Fig. 1 Technologies for mixed A/D applications.

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Analog Technology & Design Techniques Requirements for Monolithic Integration

Scaling of operational devices -
to realize a large number of devices
on the same substrate

Isolation of the devices

Reliability & yield in production

Design Techniques for (Very) Large Scale Integration

- Inductors can not be integrated
- Minimise the no. of passive components & values substitute resistors with active devices if possible.
- Active devices can be used in large numbers.
- Use ratio of parameters than absolute values
- Identify the really critical specifications to implement the right trade-offs
- If possible do the processing in Digital Domain

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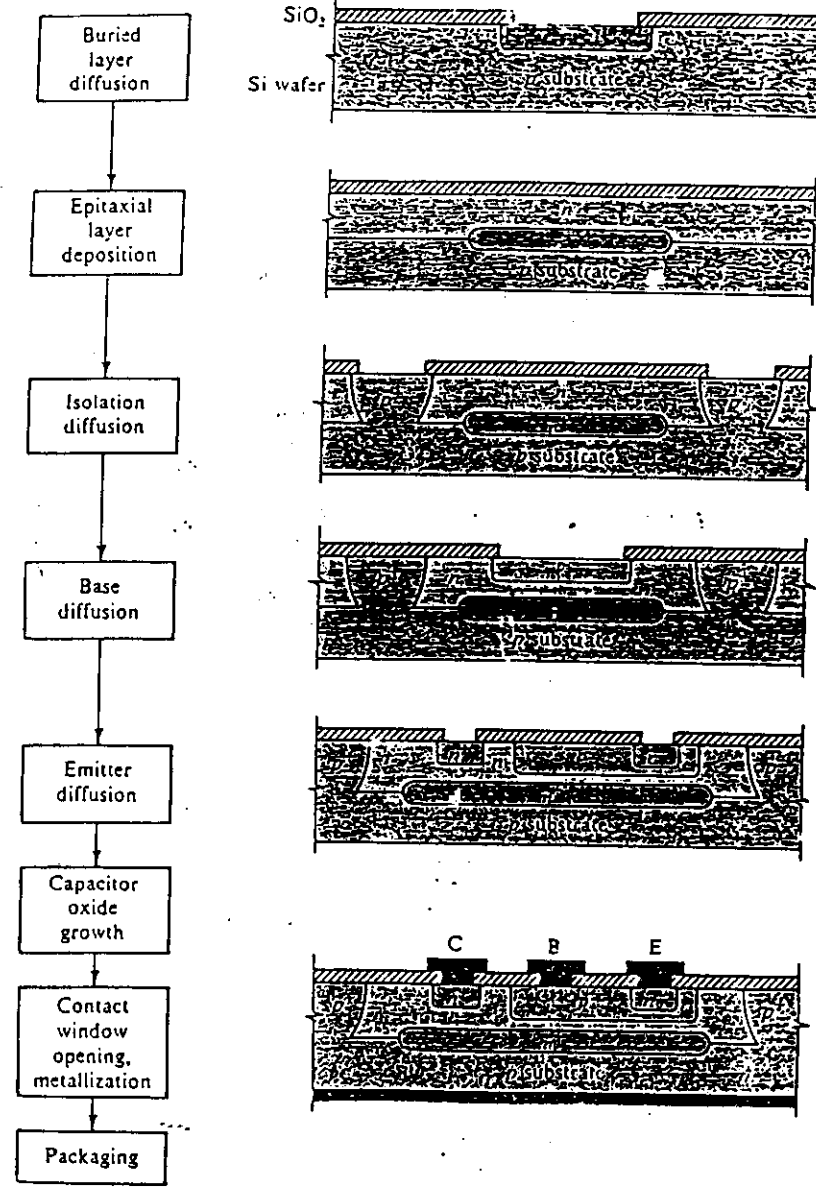


Fig. A.1 Standard bipolar Integrated-circuit process.

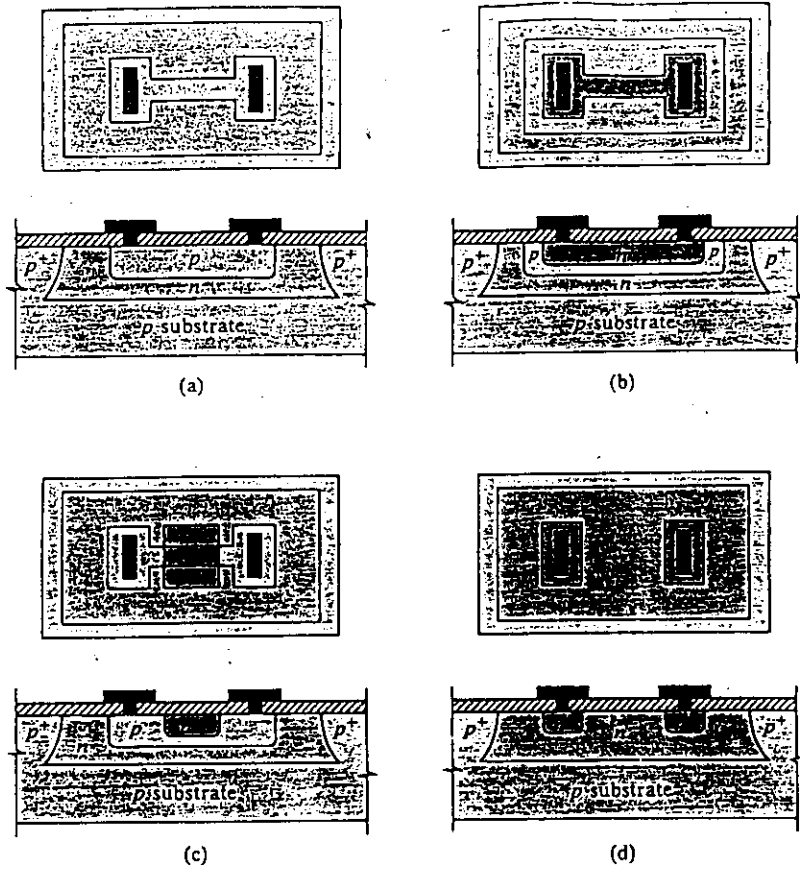


Fig. A.2 Integrated-circuit resistor structures. (a) Base resistor. (b) Emitter resistor. (c) Pinched base resistor. (d) Collector resistor.

Table A.1 DIFFUSED RESISTOR CHARACTERISTICS

	Resistor Type			
	Base	Emitter	Pinched Base	Collector
Range (ohms)	50-50 k	5-100	10 k-500 k	1 k-10 k
Tolerance	20%	20%	50%	50%
Matching	5%	5%	5%	5%
Temperature coefficient	0.1%/°C	0.2%/°C	0.5%/°C	0.8%/°C
Breakdown voltage (V)	40	6	6	70

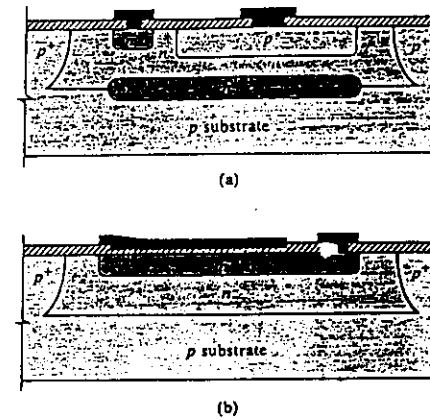


Fig. A.3 Integrated-circuit capacitor structures. (a) Collector-base junction capacitor. (b) Oxide capacitor.

Bipolar Junction Transistors

Three basic types of bipolar transistors are available: *npn*, *lateral pnp*, and *substrate pnp*. The *npn* structure is repeated in cross-section form in Fig. A.4. It has a beta typically of 100 to 500, a collector breakdown voltage of 40 V, and a cutoff frequency of 500 MHz. The normal operating-current range is from a few microamperes to

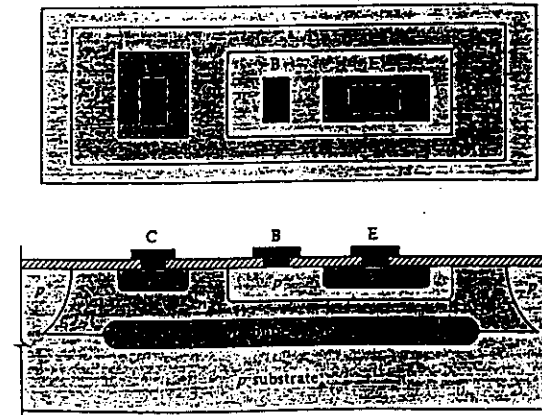


Fig. A.4 An *npn* bipolar transistor.

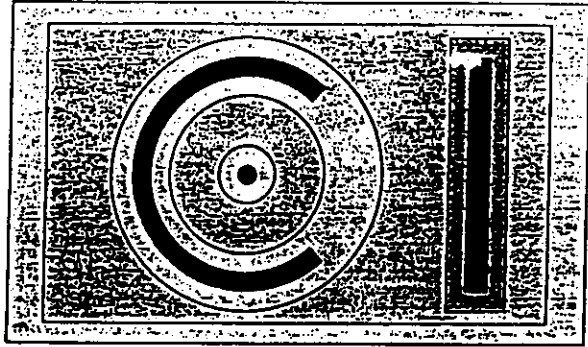
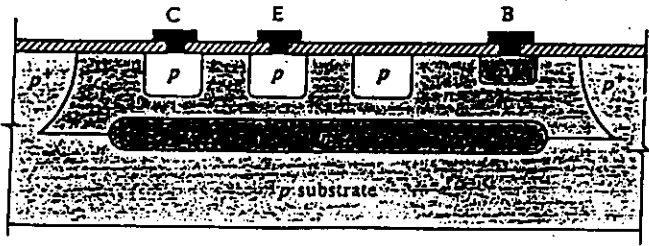


Fig. A.5 Lateral *pnp* bipolar transistor.

A-10 INTEGRATED-CIRCUIT TECHNOLOGY

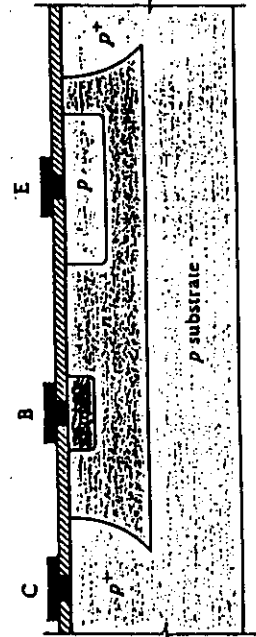
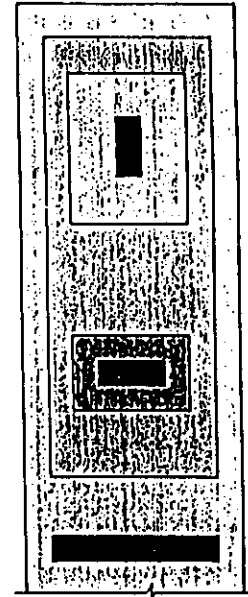
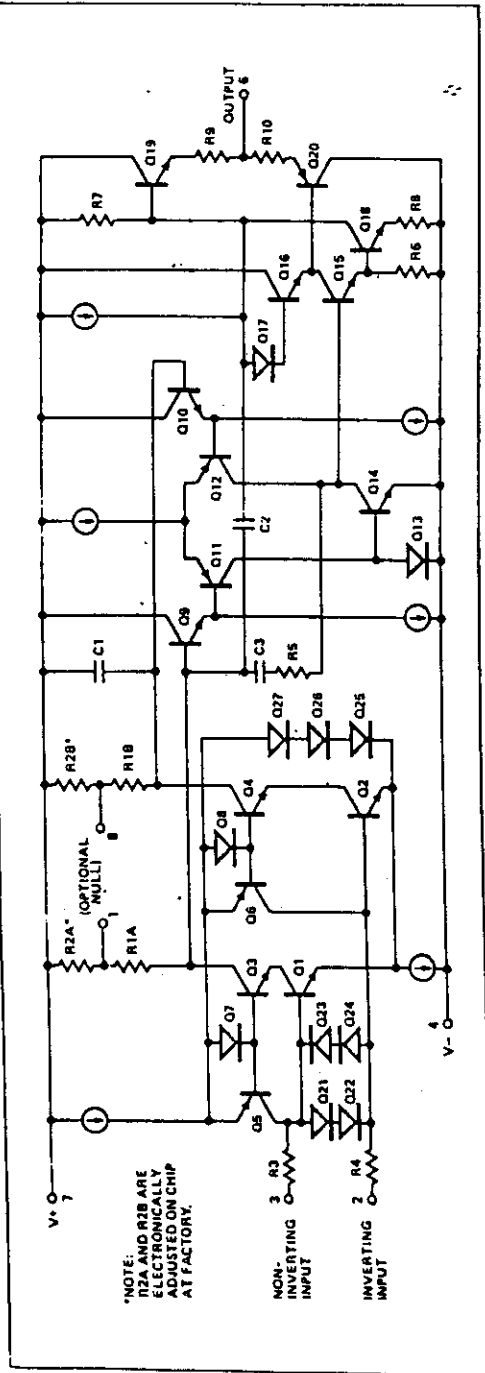


Fig. A.6. Substrate *pnp* bipolar transistor.

SIMPLIFIED SCHEMATIC



This preliminary product information is based on testing of a limited number of devices. Final specifications may vary. Please contact local sales office or distributor for final data sheet.

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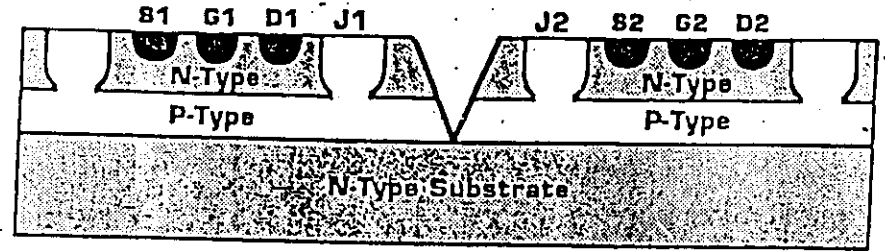


Fig. 3. JFET manufacturing process using double layer epitaxy and V-groove isolation.

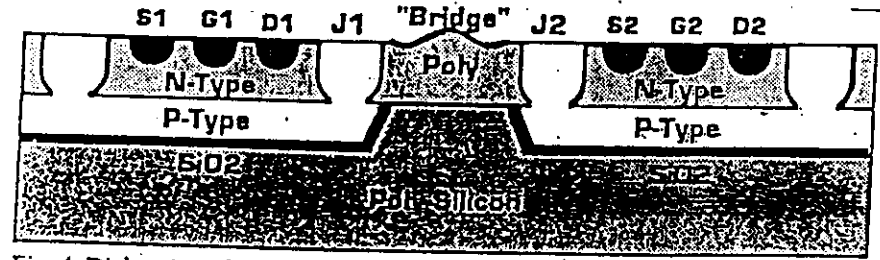


Fig. 4. Dielectric Isolation planar process.

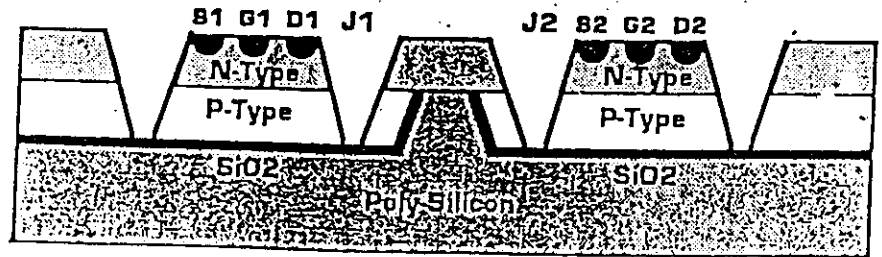
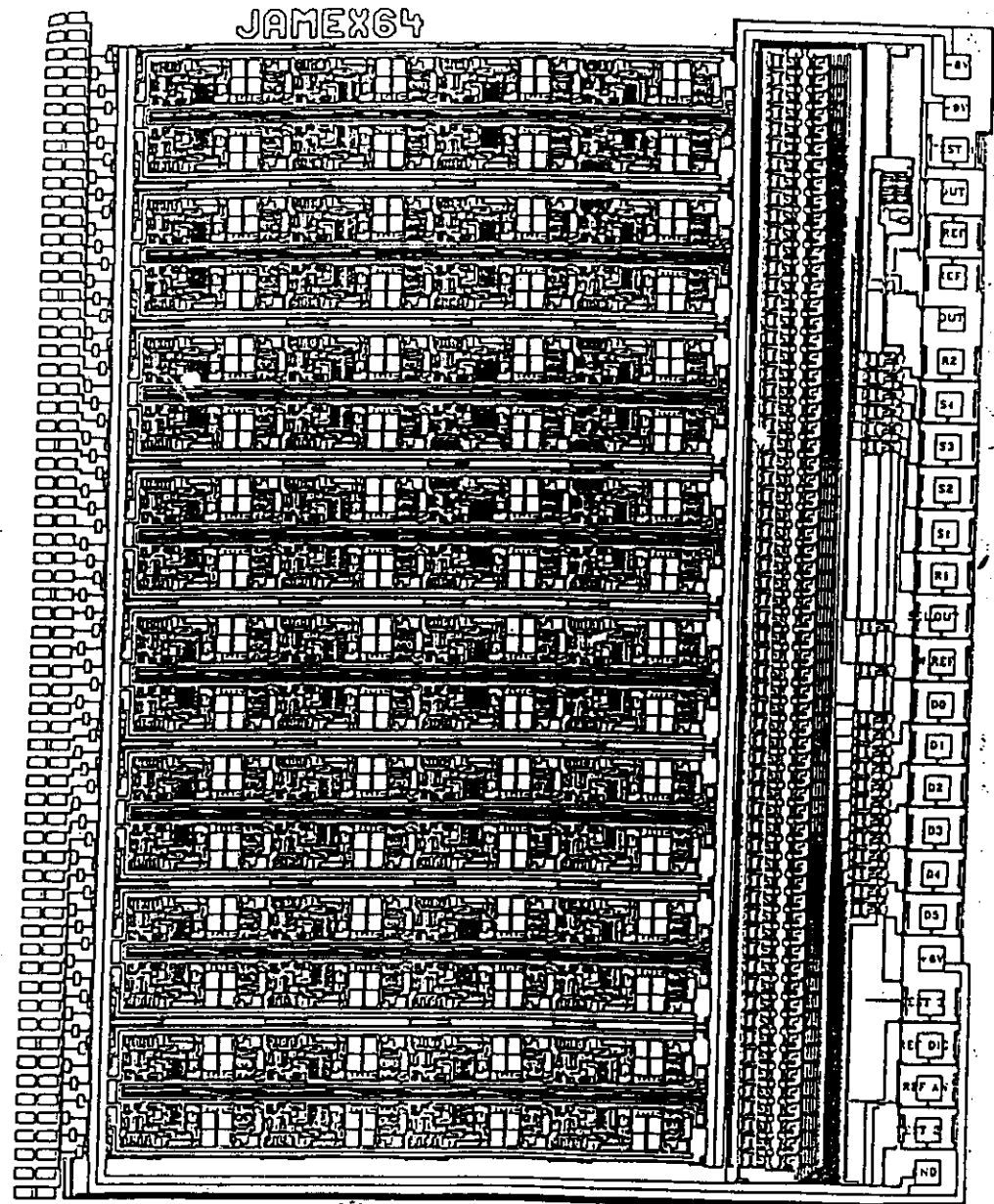
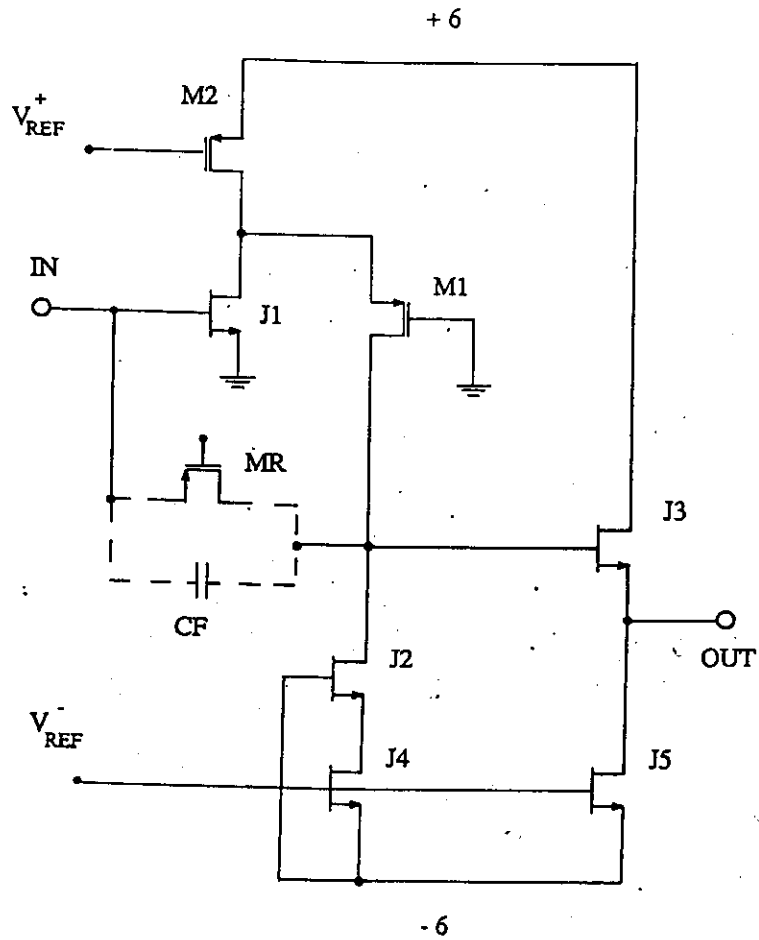
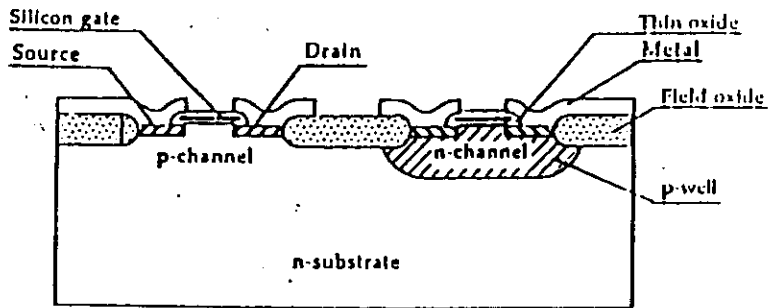


Fig. 5. Dielectric Isolation with single layer epitaxy. Mesa process, multiple tubs.

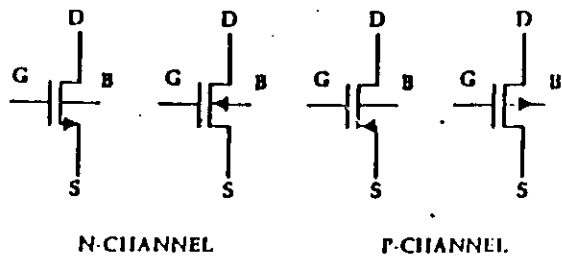
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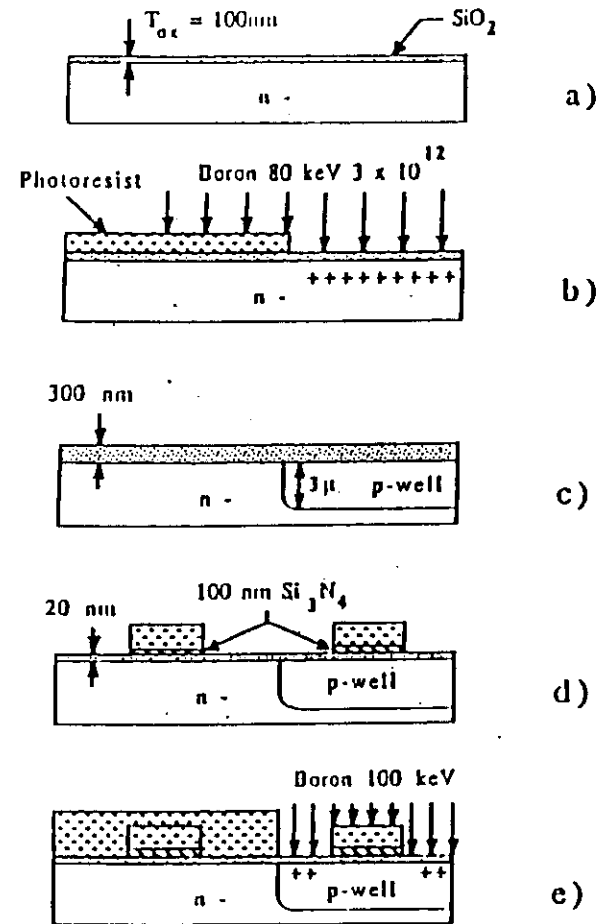
THE CMOS TECHNOLOGY

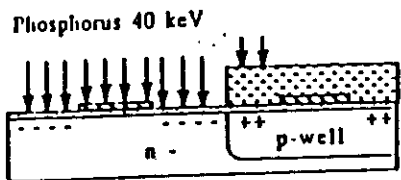


SYMBOLS OF THE MOS TRANSISTORS

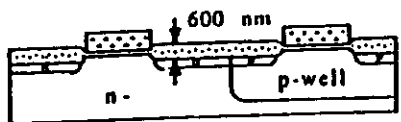


TYPICAL CMOS PROCESS

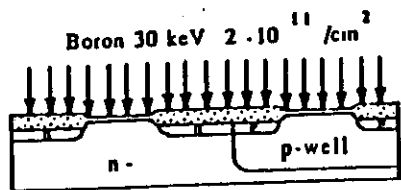




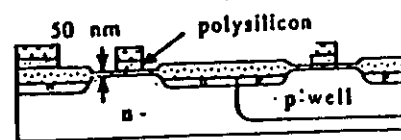
f)



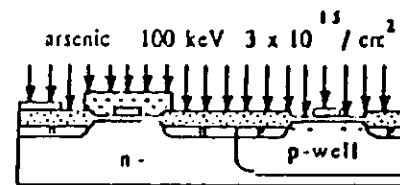
g)



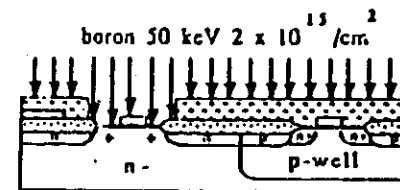
h)



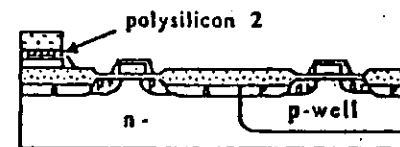
i)



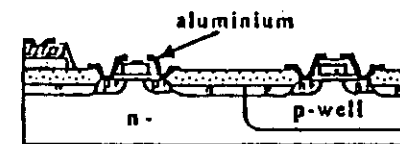
j)



k)



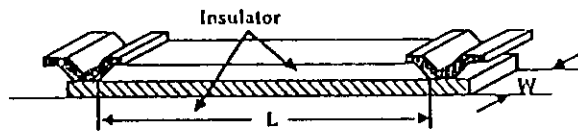
l)



m)

TYPES OF INTEGRATED RESISTORS

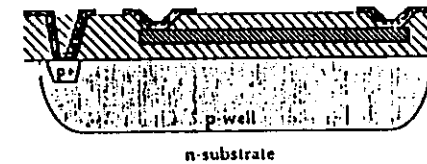
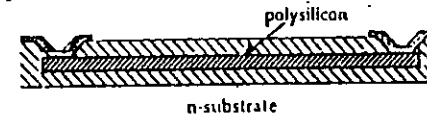
A resistor is made of a strip of resistive layer.



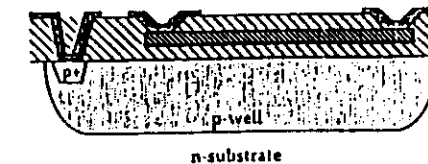
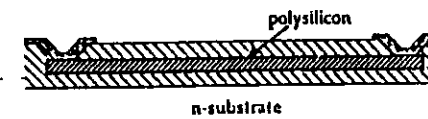
$$R = 2 \cdot R_{\text{cont}} + R_a \frac{L}{W}$$

Type of layer	Sheet res. Ω/\square	Accuracy %	TC ppm/ $^{\circ}\text{C}$	VC ppm/V
n ⁺ diffusion	30-50	25-50	200-1K	50-300
p ⁺ diffusion	50-150	25-50	200-1K	50-300
n-well	3K-5K	25	5K	10K
pinched p-well	5K-10K	50	10K	20K
pinched n-well	1K-3K	25	5K	10K
p-well	3K-6K	50	10K	20K
first poly	40-60	50	500-1.5K	20-200
second poly	25-40	50	500-1.5K	20-200

First poly resistance



Second poly resistance

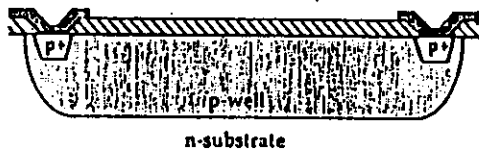


Types of resistances:

Diffused resistance



p-well (or n-well) resistance



Pinched p-well (or n-well) resistance

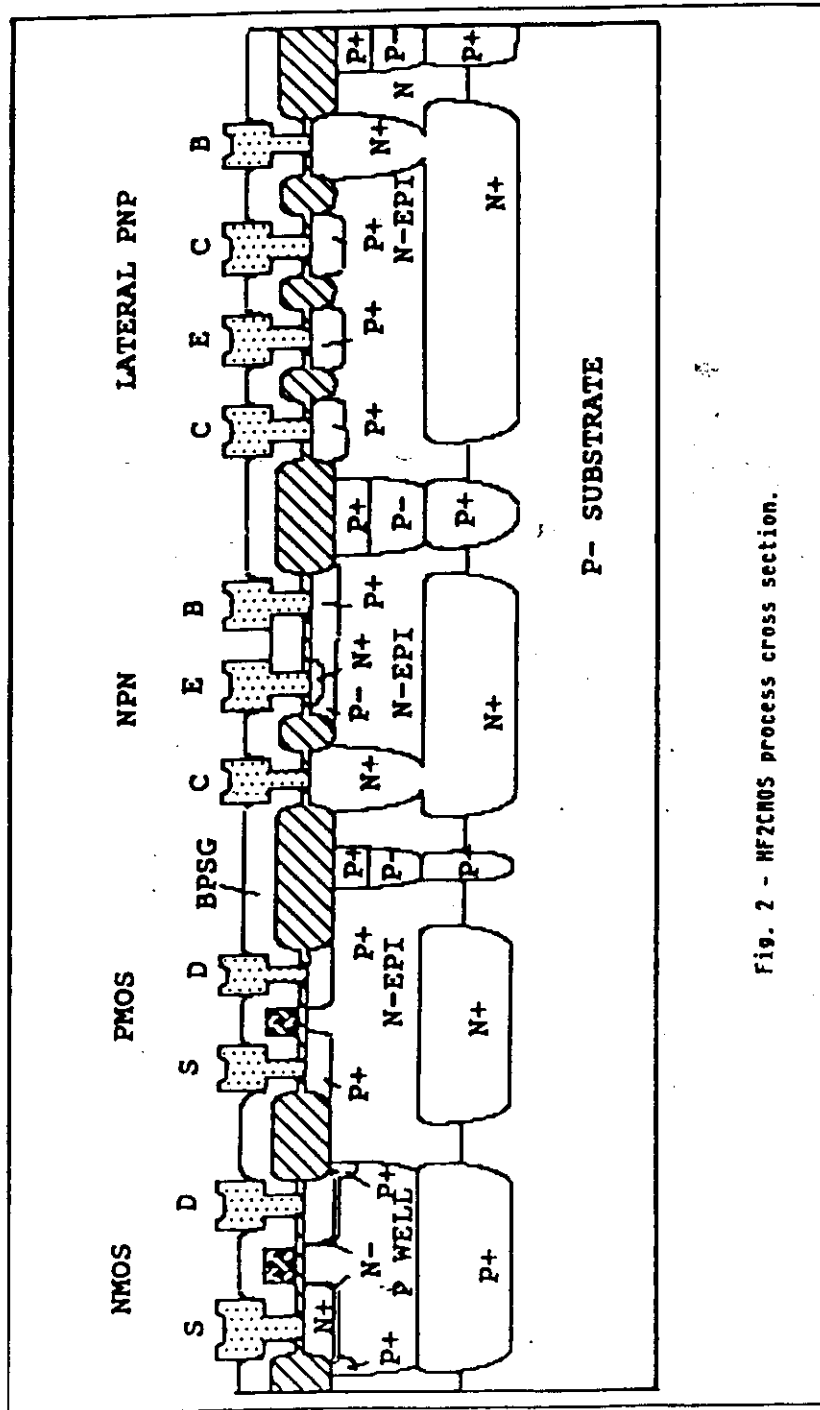
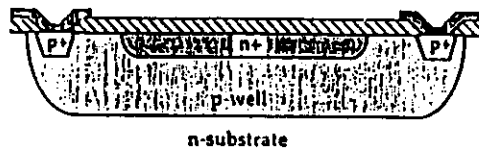


Fig. 2 - HF2CMOS process cross section.

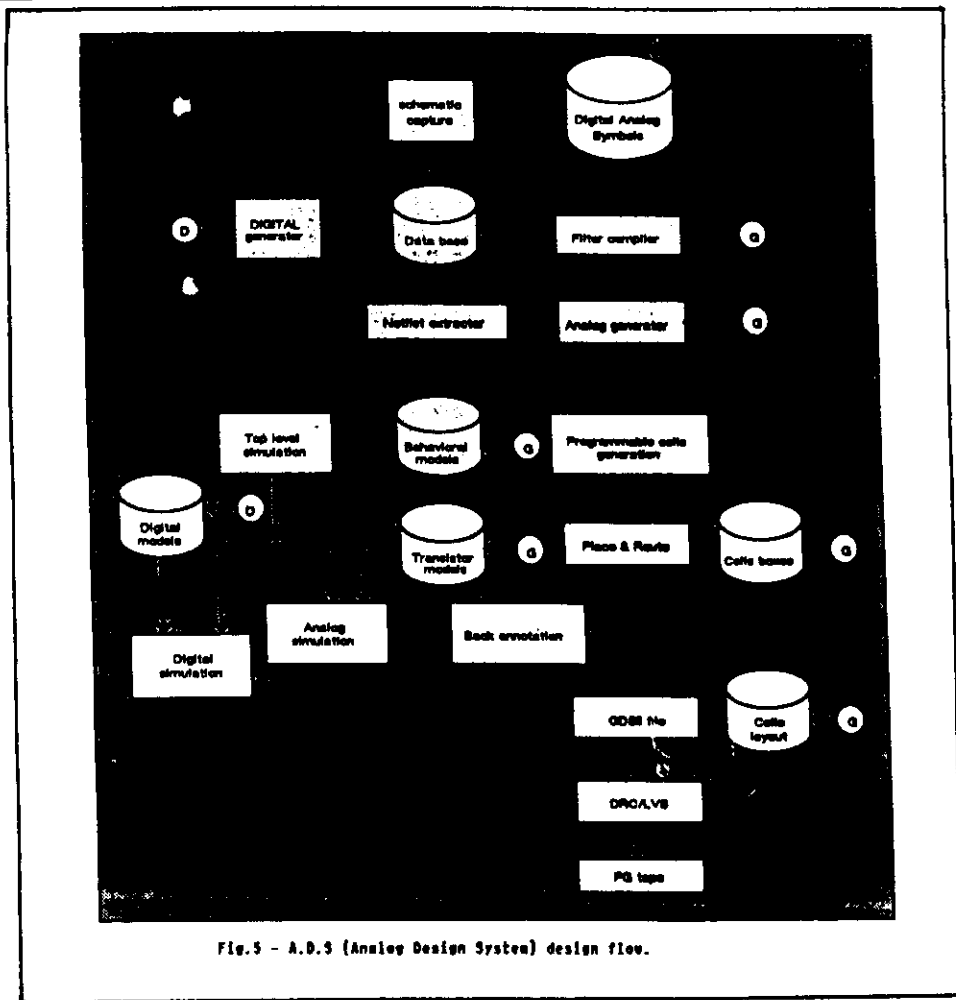


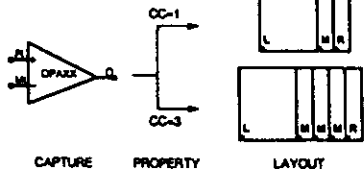
Fig.5 - A.D.S (Analog Design System) design flow.

Cell code	Description	Parameters Test conditions	Min	Typ	Max	Unit
CMP11	Static CMOS comparator	Propagation delay (overdrive = 5 mV) Offset		1 +/- 3	1.4 +/- 10	μ S mV
CMP31	Static BiCMOS comparator	Propagation delay (overdrive = 5 mV) Offset		90 +/- 2	110 +/- 7	ns mV
CPX11	Capacitor fields	Unit capacitance Capacitor value range Absolute accuracy Matching (capacitor ratio)	0.1	0.1 0.5	50 +/- 15 1.0	pF pF % %
CPP11	Monolithic capacitor	Capacitor range Absolute accuracy	1		100 +/- 15	pF %
RPM/PPM	Resistor/Potentiometer P - Base	Resistor value range Absolute accuracy Matching Temperature coefficient Voltage coefficient	6.5		3000 +/- 20 +/- 1 0.2 0.05	K Ω % % % %
SW1	Analog switch	Elementary switch RON value Number of switches in parallel	1	5	25 3	K Ω
MN11	Telescopic NMOS transistor	RON value		100		Ω
OPA31	General purpose MOS Operational amplifier	Unity gain bandwidth Current consumption Phase margin (C1 = 100 pF, R2 = 10 K Ω) Offset		3.3 700 80 +/- 3	4.8 +/- 10	MHz μ A mV
OPA41	Internal bipolar Op-Amp.	Unity gain-bandwidth current consumption Phase margin (CL = 15 pF, RL = 100 K Ω) Offset		8 240 62 +/- 1	40 +/- 5	MHz μ A mV
OPA71	Rail to rail external MOS operational Amplifier	Unity gain bandwidth Current consumption Phase margin (CL = 100 pF, RL = 100 K Ω) Offset		2.3 360 80 +/- 3	 +/- 10	MHz μ A mV
OTA11	MOS transconductance amplifier	Unity gain-bandwidth (CL = 2 pF)		24		MHz
POR11	Programmable power or Reset	Active level accuracy Hysteresis accuracy			+/- 5 +/- 5	% %
VRF11	Voltage bandgap reference	Output voltage accuracy Temperature coefficient Current consumption		15	+/- 2 100	% ppm μ A
OSC11	Programmable crystal oscillator	Frequency	0.1		20	MHz
OSC41P	RC oscillator	Frequency Stability versus temperature Stability versus voltage	1	100 0.01 0.5	800	KHz %/°C %/V
OSC31P	One pad I.C oscillator	Frequency Stability versus temperature Stability versus voltage	2	0.01 0.5	200	KHz %/°C %/V
SCF	Filters	Order Center frequency	2		12 100	KHz
ADC81	8 bit analog to digital converter	Conversion time Integral non linearity Differential non linearity			5 +/- 0.5 +/- 0.5	μ S LSB LSB
DAC81	8 bit digital to analog converter	Conversion time (CL = 2 pF) Integral non linearity			1 +/- 0.5	μ S LSB

TABLE 1 : STKM2000 Analog Library abstract

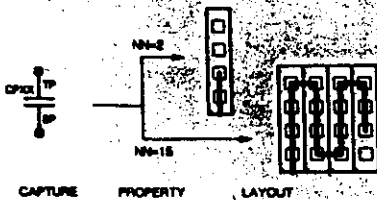
Fig. 4 : MIXED A/D LIBRARY MANAGEMENT

A - TELESCOPIC CELLS



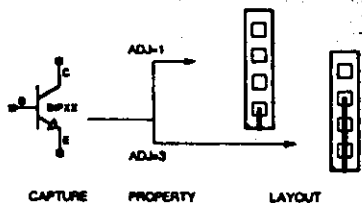
- Cell is compiled by abutment of subcells, selected among a library of leaf cells: one left-side subcell, then a given number of middle subcells, to reach the value selected by the property, and finely one right-side subcell.
 - Concerned cells in STKM2000 library are: digital output buffers, operational amplifiers, monolithic capacitors, MOS transistors, ...

B - PARAMETRISABLE CELLS

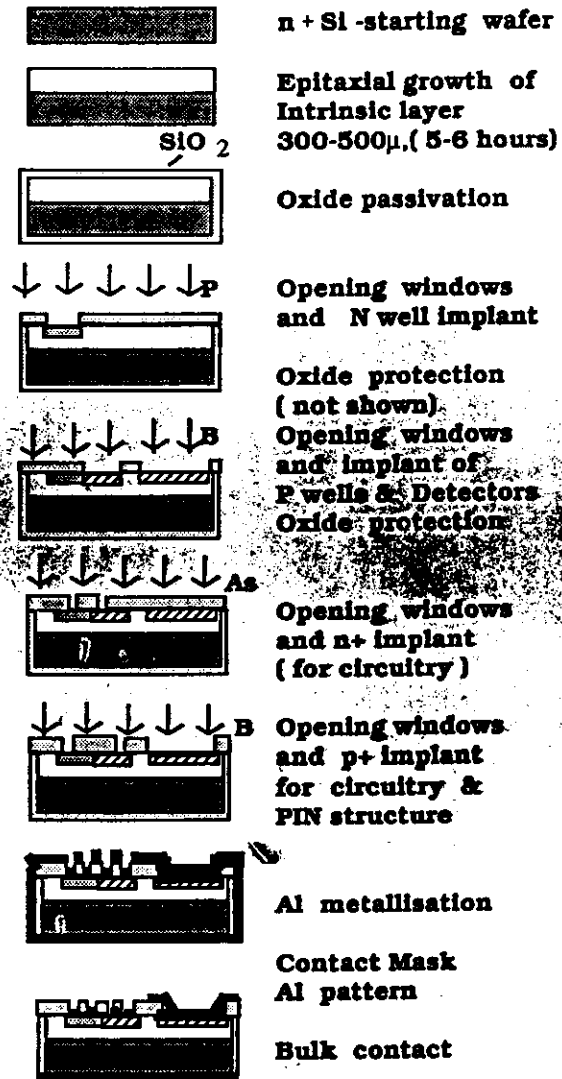


- An array of devices is compiled by abutment of subcells. Some end cells are added at the right of the array to fit a grid multiple cell width.
 - A metal line is added to customize this field of devices (like a gate array personalisation) at their exact value.
 - Concerned cells in STKM2000 library are: capacitance fields (3 different kinds) and resistance fields (5 different kinds).

C - ADJUSTABLE CELLS



- Personalization figures are added upon a predesigned cell to customize its functionality.
 - Concerned cells in STKM2000 library are: bipolar transistors, switches, power-on-reset, pull-up and pull-down resistances, ...



CONCLUSIONS

1. Analog IC Design is strongly dependant on the IMPLEMENTATION-TECHNOLOGY and the choice of components available within.
2. Design implementations use -
Maximum no. of active components and
minimum no. and value of passive components.
3. Design with ratio of parameters than
absolute value.
4. Technological choices
Bipolar } Bulk technology (LSI)
JFET } Isolation problems.
CMOS → "Surface technology (VLSI)
Low power / lower performance of gain etc.
Self isolated (SSC)
Bi. CMOS → Largest range of options.
Expensive.
Special purpose CMOS → for low-noise applications
high speed.
5. Design automation is minimal.
Custom design more prevalent.

General Information on foundries

1. MOSIS - Fast prototyping services for full custom VLSI.
Low cost (\$500 for 4 ports)
(available for users in USA) - 2 pr / 1 hr
Information can be obtained without being a user.
E-mail to University of Southern California.
Refnet: MOSIS / MOSIS.EDU @ MOSIS.EDU
Mosis currently offers low-noise analog process by ORBIT.
2. ORBIT Semiconductor 1230 Bordeaux Dr.
Sunnyvale, CA 94089
Fax: 408 747 1263
ORBIT FORESIGHT PROGRAM - low cost (for announcement
\$1500 for 12 ports)
No restrictions.
Contact person: ALASDAIR DENTON-MILLER
17 Bridge Street, Leatherhead, Surrey
KT 22 8BL ENGLAND.
Phone: (0372) 376848.
3. SGS-THOMSON Microelectronics
Avenue de Martiens
Grenoble, FRANCE
Powerful Bi-CMOS process and design automation tools.
4. INVIOMECC - Belgium.

